



Attorney Docket # 5367-47RCE2

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Stefan BADER et al.

Serial No.: 10/696,882

Filed: October 30, 2003

For: Method for Depositing a Material on a Substrate
Wafer

Examiner: RAO, G. Nagesh
Group Art: 1722

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

April 2, 2008

(Date of Deposit)

Lance J. Lieberman

Name of applicant, assignee or Registered Representative

Signature

April 2, 2008

Date of Signature

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

SIR:

Responsive to the Office Action dated January 2, 2008, please amend the above-identified application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 5 of this paper.